			Or -
Notice of Allowability	Application No.	Applicant(s)	1
	10/781,689	MIYA ET AL.	
	Examin r	Art Unit	
	Parviz Hassanzadeh	1763	
The MAILING DATE of this communication appears n the cover sheet with the correspondence address All claims being allowable, PROSECUTION ON THE MERITS IS (OR REMAINS) CLOSED in this application. If not included herewith (or previously mailed), a Notice of Allowance (PTOL-85) or other appropriate communication will be mailed in due course. THIS NOTICE OF ALLOWABILITY IS NOT A GRANT OF PATENT RIGHTS. This application is subject to withdrawal from issue at the initiative of the Office or upon petition by the applicant. See 37 CFR 1.313 and MPEP 1308.			
1. This communication is responsive to <u>11/12/04</u> .			
2. The allowed claim(s) is/are 14,15 and 17-19.			
3. The drawings filed on 20 February 2004 are accepted by the Examiner.			
<ul> <li>4.  Acknowledgment is made of a claim for foreign priority una)  All b)  Some* c)  None of the:  1.  Certified copies of the priority documents have 2.  Certified copies of the priority documents have 3.  Copies of the certified copies of the priority do International Bureau (PCT Rule 17.2(a)).  * Certified copies not received:  Applicant has THREE MONTHS FROM THE "MAILING DATE" noted below. Failure to timely comply will result in ABANDONN THIS THREE-MONTH PERIOD IS NOT EXTENDABLE.</li> <li>5.  A SUBSTITUTE OATH OR DECLARATION must be subm INFORMAL PATENT APPLICATION (PTO-152) which give 6.  CORRECTED DRAWINGS (as "replacement sheets") must (a)  including changes required by the Notice of Draftspers</li> </ul>	e been received. e been received in Application No. 10 cuments have been received in this of this communication to file a reply MENT of this application.  iitted. Note the attached EXAMINER es reason(s) why the oath or declarate st be submitted. son's Patent Drawing Review (PTO-	national stage application to complying with the require 'S AMENDMENT or NOTIC tion is deficient.	ements
1) ☐ hereto or 2) ☐ to Paper No./Mail Date  (b) ☐ including changes required by the attached Examiner's Amendment / Comment or in the Office action of Paper No./Mail Date			
Identifying indicia such as the application number (see 37 CFR 1 each sheet. Replacement sheet(s) should be labeled as such in t	.84(c)) should be written on the drawing the header according to 37 CFR 1.121(	ngs in the front (not the bac d).	k) of
7. DEPOSIT OF and/or INFORMATION about the deposit of BIOLOGICAL MATERIAL must be submitted. Note the attached Examiner's comment regarding REQUIREMENT FOR THE DEPOSIT OF BIOLOGICAL MATERIAL.			
Attachment(s)  1. Notice of References Cited (PTO-892)  2. Notice of Draftperson's Patent Drawing Review (PTO-948)  3. Information Disclosure Statements (PTO-1449 or PTO/SB/O Paper No./Mail Date  4. Examiner's Comment Regarding Requirement for Deposit of Biological Material	6. ☐ Interview Summary Paper No./Mail Da 08), 7. ☐ Examiner's Amendr	te	
-	<u> </u>		

## **DETAILED ACTION**

## Allowable Subject Matter

Claims 14, 15 and 17-19 are allowed.

The following is an examiner's statement of reasons for allowance: a method of diagnosing a processing apparatus including a vacuum process chamber wherein a semiconductor is treated by a plasma generated from a gas, the method comprising steps of:

imparting mechanical oscillation to the semiconductor processing apparatus; detecting the mechanical oscillation signals generated by imparting mechanical oscillation inside the apparatus; and analyzing detected signals to diagnose whether the vacuum process chamber is normally assembled and to specify a position inside the vacuum chamber which an abnormality has occurred. In another embodiment, the method determines a resonant frequency of a component by changing the frequency of the imparted mechanical oscillation to diagnose a condition of the component. In yet another embodiment, the oscillation imparting device and the reception device are juxtaposed with each other on a sidewall of the chamber, and the method includes analyzing the detected signals to evaluates the thickness of a film formed on an inner wall of the chamber.

The closest prior art by Sakamoto et al teach an apparatus including an ultrasonic pulse generator and an oscillator measuring device for detecting the end point of a plasma etching process.

Any comments considered necessary by applicant must be submitted no later than the payment of the issue fee and, to avoid processing delays, should preferably accompany the issue

Application/Control Number: 10/781,689 Page 3

Art Unit: 1763

fee. Such submissions should be clearly labeled "Comments on Statement of Reasons for Allowance."

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Parviz Hassanzadeh whose telephone number is (571)272-1435. The examiner can normally be reached on Tuesday-Friday.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Gregory Mills can be reached on (571)272-1439. The fax phone number for the organization where this application or proceeding is assigned is 703-872-9306.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

P. Hassanzadeh Parviz Hassanzadeh Primary Examiner Art Unit 1763

December 16, 2004